

SR-EUV/200/150 FULLY AUTOMATIC RETICLE POD CLEANING SYSTEM



OVERVIEW

The SR-EUV/200/150 is Hugle's fully automatic cleaning system for EUV Reticle PODs, RSP-200 and RSP-150. Cleaning these pods is one of the most demanding applications for container cleaning equipment in the Semiconductor Industry. Hugle has met the challenge with innovative technology and unmatched system reliability. The EUV pod is automatically fed into the system, outer and inner pods are disassembled and placed into separate cleaning chambers where they are washed and dried using our unique technology. They are then reassembled and delivered to the load port..In the case of RSP-200 and RSP-150 only one cleaning chamber is included. Pods are efficiently washed and dried without exceeding recommended temperatures. The SR-EUV/200/150 successfully removes nanometer sized particles in a fully automatic on line system compatible with industry standards.



CHIP HUA EQUIPMENT & TOOLS PTE LTD. 集華儀器與器具(私人)有限公司

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FEATURES

- Small Foot print
- Unique cleaning technology
- Completely dry by high efficiency drying method
- Fully automatic open/close pod for preventing cross-contamination
- Also cleans RSP200
- Built in Robot hand self cleaning system
- Inner pod cleaning chamber(Not included for RSP-200/150)
- Outer pod cleaning chamber
- Pods can be loaded manually

SPECIFICATIONS

- Main System: 1230mm(W) x 2900mm(D) x2300mm(H) (Excluded any projections)



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